

## **Development of nanostructures for thermoelectric microgenerators using ion-track lithography**

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A novel fabrication process for nanostructures for thermoelectric microgenerators, based on a combination of a traditional silicon microfabrication techniques, electroplating and submicron ion-track nanolithography, is discussed. Ion-track etched polyimide nanotemplates (30–80 nm pore diameters) are used to grow  $\text{Bi}_2\text{Te}_3$  nanowires by electroplating. The  $\text{Bi}_2\text{Te}_3$  film's microstructural and thermoelectric properties are reported.